

APPARATUS AND METHOD FOR ELECTROMECHANICAL TESTING AND VALIDATION OF PROBE CARDS

ABSTRACT OF THE DISCLOSURE

A method of testing a probe card includes the step of positioning the probe card in a prober over a verification wafer that is placed on a stage. The probe card is brought in contact with a contact region on the verification wafer. The verification wafer includes a shorting plane surrounding the contact region. A test signal is sent through the verification wafer to the probe card. A response signal from the probe card is received and analyzed.

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